

EV318282305

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Application Serial No. 09/298,160
Filing Date April 22, 1999
Inventor Dan G. Custer et al.
Assignee Micron Technology, Inc.
Group Art Unit 1763
Examiner A.W. Olsen
Attorney's Docket No. MI22-1172
Title: Polishing Systems, Method of Polishing Substrates, and Methods of Preparing
Liquids for Semiconductor Fabrication Processes

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to
the United States patents and other references listed on the attached Form PTO-1449.

No admission is made regarding whether all the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: _____

9-26-03

D. Brent Kenady
Reg. No. 40,045
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828
(509) 624-4276

10/02/2003 KBETEM1 00000140 09298160

02 FC:1806

180.00 OP

Form PTO 1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1172		SERIAL NO. 09/298,160	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Dan G. Custer et al.	
FILING DATE April 22, 1999				GROUP	

OIPE
 SEP 26 2003
 PATENT & TRADEMARK OFFICE

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,416,676 B1	07/09/02	Hill			
	AB	5,766,321	06/16/98	Ishihara et al.			
	AC	5,110,741	05/05/92	Ohi et al.			
	AD	4,894,342	01/16/90	Guinn et al.			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
	AL	WO 94/23816	PCT			Yes	No
	AM						
	AN						
	AO						
	AP						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AR	Hodgman, M.S., Charles D., "Handbook of Chemistry and Physics	A Ready-Reference Book of Chemical and
		Physical Data," 27 Ed., ©1910, 3 pages.	
	AS		
	AT		

EXAMINER	DATE CONSIDERED
----------	-----------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.